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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/634,010	08/04/2003	Ralph N. Wall	55123P244	5811	
8791	7590 05/10/2004		EXAM	INER	
BLAKELY SOKOLOFF TAYLOR & ZAFMAN			HASAN, MOHAMMED A		
12400 WILSHIRE BOULEVARD, SEVEN LOS ANGELES, CA 90025		TH FLOOR	ART UNIT	PAPER NUMBER	
200111102	2, 211 / 1112		2873		
			DATE MAILED: 05/10/200	4	

Please find below and/or attached an Office communication concerning this application or proceeding.

<del> </del>		Application No.	Applicant(s)			
Office Action Summary		10/634,010	WALL ET AL.			
		Examiner	Art Unit			
		Mohammed Hasan	2873	Au		
Period fo	The MAILING DATE of this communication ap or Reply	pears on the cover sheet with	the correspondence addi	ress		
THE - Exte after - If the - If NO - Failu Any	ORTENED STATUTORY PERIOD FOR REPL MAILING DATE OF THIS COMMUNICATION. nsions of time may be available under the provisions of 37 CFR 1. SIX (6) MONTHS from the mailing date of this communication. e period for reply specified above is less than thirty (30) days, a replay to period for reply is specified above, the maximum statutory period reto reply within the set or extended period for reply will, by staturely received by the Office later than three months after the mailined patent term adjustment. See 37 CFR 1.704(b).		oly be timely filed (30) days will be considered timely. HS from the mailing date of this com NDONED (35 U.S.C. § 133).	nmunication.		
Status						
1)	Responsive to communication(s) filed on	·				
2a) <u></u> □	This action is <b>FINAL</b> . 2b)⊠ Thi	s action is non-final.				
3)□	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.					
Disposit	ion of Claims					
5)□ 6)⊠ 7)⊠	Claim(s) <u>1 - 29</u> is/are pending in the application 4a) Of the above claim(s) is/are withdrated claim(s) is/are allowed.  Claim(s) <u>1,2, 4- 10, 14, 18 - 20, 23 - 25</u> is/are Claim(s) <u>3, 11- 13, 15 - 17, 21, 22, 26 - 29</u> is/Claim(s) are subject to restriction and/or	rejected. /are objected to.				
Applicati	on Papers					
9)[	The specification is objected to by the Examin	er.				
10)⊠	The drawing(s) filed on <u>04 August 2003</u> is/are.	: a)⊠ accepted or b)⊡ obje	ected to by the Examiner.			
	Applicant may not request that any objection to the	e drawing(s) be held in abeyanc	e. See 37 CFR 1.85(a).			
11)	Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the E		•	• •		
Priority ι	ınder 35 U.S.C. § 119					
a)(	Acknowledgment is made of a claim for foreign All b) Some * c) None of:  1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority document application from the International Bureasee the attached detailed Office action for a list	ts have been received. ts have been received in Appority documents have been re au (PCT Rule 17.2(a)).	plication No eceived in this National St	tage		
Attachmen	t(s)					
	e of References Cited (PTO-892)	4) Interview Su				
3) 🔲 Inform	e of Draftsperson's Patent Drawing Review (PTO-948) nation Disclosure Statement(s) (PTO-1449 or PTO/SB/08 r No(s)/Mail Date		Mail Date  promal Patent Application (PTO-1  .	152)		

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#### **DETAILED ACTION**

#### Oath/Declaration

1. Oath and declaration filed on 8/4/2003 is accepted.

## Claim Rejections - 35 USC § 103

- 2. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1, 2, 4 – 10, 14, 18 – 20, 23 – 25 are rejected under 35 U.S.C. 103(a) as being unpatentable over Okura et al (US 2002/0126265) in view of Miura et al (6,242,792 B1).

Regarding claim 1, Okura et al discloses (refer to figure 4) a device having a reflection layer (82), a dielectric layer (81) (paragraph 0175). Okura discloses all of the limitations except a thin film resistor formed over the dielectric layer. However, Miura et al discloses (refer to figure 1) a thin film resistor 3 (column 6, line 40). It would have been obvious to one of ordinary skill in the art at the time the invention was made to provide a thin film resistor in to the Okura an optical device for the purpose of laser-trimmed with a high degree of precision without precise control of a height of a top portion as taught by Miura et al (column 3, lines 10 – 15).

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Regarding claim 2, Okura et al discloses, reflector comprises a refractory metal (paragraph 0175).

Regarding claim 4, Miura et al discloses, laser energy used to laser trimming thin film resistor (3) (column3, lines 10 - 15).

Regarding claim 5, Okura et al discloses first dielectric layer (81) is a predetermined thickness range, which optimizes the laser trimming of thin film resistor (paragraph 0175).

Regarding claim 6, Okura et al discloses first dielectric layer comprises silicon dioxide (SiO<sub>2</sub>) (paragraph 0175).

Regarding claim 7, Miura et al discloses thin film resistor comprises chromium silicon (CrSi), nickel chromium (NiCr) and or tantalum nitride (TaN) (column 6, line 40).

Regarding claim 8, Okura et al discloses (refer to figure 4) a second dielectric layer (83) (paragraph 0175).

Regarding claim 9, Okura et al discloses a second dielectric layer (83) is a predetermined thickness range which optimizes the laser trimming of thin film resistor (paragraph 0175).

Regarding claim 10, Okura et al discloses second dielectric layer comprises silicon dioxide (SiO<sub>2</sub>) (paragraph 0175).

Regarding claim 14, Okura et al discloses (refer to figure 4) a device having a reflection layer (82), a dielectric layer (81) (paragraph 0175). Okura discloses all of the limitations except a thin film resistor formed over the dielectric layer. However, Miura et al discloses (refer to figure 1) a thin film resistor 3 (column 6, line 40) It would have

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been obvious to one of ordinary skill in the art at the time the invention was made to provide a thin film resistor in to the Okura an optical device for the purpose of laser-trimmed with a high degree of precision without precise control of a height of a top portion as taught by Miura et al (column 3, lines 10 - 15).

Regarding claim 18, Miura et al discloses laser energy used to laser trimming thin film resistor (3), wherein reflector substantially reflects laser energy towards thin film resistor (column3, lines 10 - 15).

Regarding claim 19, Okura et al discloses first dielectric layer (81) is a predetermined thickness range, which optimizes the laser trimming of thin film resistor (paragraph 0175).

Regarding claim 20, Okura et al discloses first dielectric layer comprises silicon dioxide (SiO<sub>2</sub>) (paragraph 0175).

Regarding claim 23, Okura et al discloses (refer to figure 4) a second dielectric layer (83) (paragraph 0175).

Regarding claim 24, Okura et al discloses a second dielectric layer (83) is a predetermined thickness range which optimizes the laser trimming of thin film resistor (paragraph 0175).

Regarding claim 25, Okura et al discloses second dielectric layer comprises silicon dioxide (SiO<sub>2</sub>) (paragraph 0175).

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## Allowable Subject Matter

3. Claims 3, 11 - 13, 15 - 17, 21, 22, 26 - 29 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

- 4. The following is a statement of reasons for the indication of allowable subject matter: The prior art fails to show refractory metal comprises tungsten (w), molybdenum (Mo), tantalum (Ta), Rhenium (Re), and /or Niobium (Nb) and a metal insulator-metal (MIM) capacitor and a mask layer over the reflective layer and patte5rning and developing mask layer to form a mask and etching reflective layer except a portion underlying mask.
- 5. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. The closest prior art

Little (US 2003/0123125 A1) discloses detonable Fabry-Perot interferometer and a method of tuning a Fabry-Perot interferometer provided.

### Conclusion

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Mohammed Hasan whose telephone number is (571) 272-2331. The examiner can normally be reached on M-TH, 7:00 AM to 5:30 PM.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Georgia Epps can be reached on (571) 272- 2328. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

MH April 27, 2004

> Gdorgia Euros Supervisory Patent Examiner Technology Center 2800